

**Reply Under 37 C.F.R. § 1.116  
Expedited Procedure  
Technology Center 1700**

Attorney Docket No. 740756-2709

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of: )  
Koichiro TANAKA ) Confirmation No. 9528  
Application No. 10/769,820 ) Examiner: Samuel Heinrich  
Filed: February 3, 2004 ) Group Art Unit: 1793  
  
For: LASER IRRADIATION STAGE, )  
LASER IRRADIATION OPTICAL )  
SYSTEM, LASER IRRADIATION )  
APPARATUS, LASER IRRADIATION )  
METHOD, AND METHOD OF )  
MANUFACTURING A )  
SEMICONDUCTOR DEVICE )

**AMENDMENT WITH RCE**

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Final Office Action mailed December 28, 2007, and together with the Request for Continued Examination concurrently filed herewith, please amend the above-identified application as follows: